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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

May 24, 2004

Applicants : Bruce M. Warnes et al.

FOR : CVD CODEPOSITION OF A1 AND ONE OR MORE

REACTIVE (GETTERING) ELEMENTS TO FORM

PROTECTIVE ALUMINIDE COATING

Serial No. : 10/645 292

Group: 1734

Filed

: Aug. 20, 2003

Examiner: Edwards

Confirmation No. 7204

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Dear Sir:

Please amend the above application as follows:

IN THE SPECIFICATION

1) Insert the following paragraph on page 1, after the title:

This application is a division of Serial No. 08/197,497 filed February 16, 1994, now U.S. Patent 6,689,422.

2) Substitute the following paragraph for the first partial paragraph (lines 1-16) on page 15:

ride. Generally, the total flow rate of the precursor halide gas stream is controlled to provide a coating gas stream S1' comprising 1 volume % or less of silicon tetrachloride, 1 to 10 volume % aluminum trichloride and the balance hydrogen. When such a coating gas stream S1' contacts a heated substrate in a CVD retort, Al and Si will be codeposited thereon and incorporated into the aluminide diffusion coating formed thereon. The cogeneration and codeposition of Al and Si in this manner is described further in copending